

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hiroji AGA et al.

Rule 53(b) Divisional of

Application No.: 09/857,803

Filed: October 15, 2003

Docket No.: 109725.01

For: METHOD FOR PRODUCING SOI WAFER AND SOI WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. The references were cited by or submitted to the Office in parent application No. 09/857,803, filed June 11, 2001, which is relied upon for an earlier filing date under 35 U.S.C. §120. Thus, copies of these references are not attached. 37 CFR §1.98(d).

Respectfully submitted,



William P. Berridge
Registration No. 30,024

Julie M. Seaman
Registration No. 51,156

WPB:JMS/jcp

Date: October 15, 2003

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 109725.01	APPLICATION NO. Rule 53(b) Divisional of Application No. 09/857,803	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT(S) Hiroji AGA et al.			
		FILING DATE October 15, 2003			
U.S. PATENT DOCUMENTS					
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS
		US-2002/0127820	09-2002	Nobuhiko SATO	
		5,989,981	11-1999	NAKASHIMA et al.	
		6,350,703	02-2002	SAKAGUCHI et al.	
		6,074,479 A	06-2000	ADACHI et al.	
		6,403,502 B1	06-2002	KOBAYASHI et al.	
		6,261,362 B1	07-2001	FUJIKAWA et al.	
		6,313,014 B1	11-2001	SAKAGUCHI et al.	
		5,937,312 A	08-1999	IYER et al.	
		5,834,812 A	11-1998	GOLLAND et al.	
		6,284,628 B1	09-2001	KUWAHARA et al.	
		6,103,599 A	08-2000	HENLEY et al.	
		6,312,797 B1	11-2001	YOKOKAWA et al.	
		5,863,832 A	01-1999	DOYLE et al.	
		6,238,990 B1	05-2001	AGA et al.	
		6,312,797 B1	11-2001	YOKOKAWA et al.	
		6,224,668 B1	05-2001	Masaro TAMATSUKA	
		6,284,629 B1	09-2001	YOKOKAWA et al.	
		6,140,210 A	10-2000	AGA et al.	
		6,245,645 B1	06-2001	MITANI et al.	
		6,251,754 B1	06-2001	OHSHIMA et al.	
		5,668,045 A	09-1997	GOLLAND et al.	
		5,494,849 A	02-1996	IYER et al.	

FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
		JP A 10-242154 (w/ Abstract)	09/11/1998	Japan		
		JP A 10-275905 (w/ Abstract)	10/13/1998	Japan		
		JP A 10-335616 (w/ Abstract)	12/18/1998	Japan		
		JP A 11-191617 (w/ Abstract)	07/13/1999	Japan		
		JP A 11-145436 (w/ Abstract)	05/28/1999	Japan		
		JP A 11-186277 (w/ Abstract)	07/09/1999	Japan		
		JP A 8-264552 (w/ Abstract)	10/11/1996	Japan		
		JP A 7-321120 (w/ Abstract)	12/08/1995	Japan		
		JP 2000-012864 A	01-2000	Japan		
		JP 11-316154 A	11-1999	Japan		
		DE 19753494 A1	10-1998	Germany		
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						
		Stanley WOLF, "silicon Processing for the VLSI Era", Vol. 1, Lattice Press, 1986, pgs. 23-25.				
EXAMINER					DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						